

REMARKS

Further consideration of this application courteously is solicited.

In Paper No. 23, the Examiner's acknowledgment of the proper establishment of a CPA in connection with the above-identified application has been appreciated. New claims 12 and 13 are hereby added to the established CPA.

Claims 6-11 have been rejected under 35 U.S.C. §103(a) as purportedly obvious over Applicant's Admitted Prior Art (AAPA) in view of U.S. Patent 6,104,986 to Arevalo. This rejection is traversed.

Independent claim 6 recites a subtle, but significant feature in the claimed invention. In the first potential detecting step, specifically substep (ii), note that the claim describes that the successive exposing of a surface portion of the photoreceptor surface with laser light corresponding to the first plurality of intensity values provides a plurality of exposed patch portions on the photoreceptor surface. Likewise, substep (ii) of the second potential detecting step recites successively exposing a surface portion of the photoreceptor with laser light corresponding to the second plurality of intensity values to provide a plurality of patch portions on the photoreceptor surface.

The nature of these "patch" portions is taught to those of ordinary skill in the art by Applicant's overall disclosure, particularly Applicant's specification and drawings.

|| Applicant's preferred examples of "patch" portions are shown in Figure 2 where they are

labeled A 1, A 2, A 3, A 4, A 5. As such, Applicant's disclosure teaches, to those of ordinary skill in the art, that the "patch" portions (as recited in the claims) are particular, defined areas on the photoreceptor surface. They are discreet areas with spacing therebetween so that reliable detection can be made of the potential existing at each of these exposed "patch" portions, after the portions have been exposed with laser light of a given intensity.

Applicant courteously submits that his AAPA and the Arevalo patent would not have taught or suggested his method as set forth in independent claim 6, irrespective of whether the AAPA and Arevalo are considered individually, or in combination. Applicant's AAPA does not teach or suggest exposure of the photoreceptor surface in a way to create Applicant's recited plurality of "exposed patch portions." This deficiency of the AAPA is not remedied by Arevalo. Applicant urges that his recited potential detecting steps simply are not taught or suggested by either the AAPA or Arevalo. That is, Applicant's substeps (ii) of both his "first potential detecting step" and his "second potential detecting step" are left undisclosed by the AAPA and Arevalo. In the absence of such teaching or suggestion, the rejection of claim 6, along with its independent claims 7-11, must fail. Withdrawal of this rejection therefore courteously is solicited.

New claims 12 and 13 are urged as allowable by virtue of their dependence from claim 6. However, these claims also recite independently patentable subject matter. Specifically, they recite further details of the "patch" portions introduced in claim 6.

In view of the foregoing comments, Applicant courteously urges that claims 6-13 patentably distinguish over the AAPA and the Arevalo patent. Further action in this application, consistent with the foregoing, courteously is solicited.

Respectfully submitted,

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LISTING OF CLAIMS

Claims 1-5 (cancelled)

6. (previously added) A laser intensity adjusting method of adjusting a maximum intensity of a laser exposure mechanism for irradiating laser light to a surface of a photoreceptor to which a uniform potential is being given by a corona discharger, said method comprising:

a first potential detecting step including the steps of (i) obtaining a first plurality of laser intensity values that increase from an initial value to a predetermined value according to a first interval to provide a first range of intensity values, (ii) successively exposing a surface portion of the photoreceptor surface with laser light having intensities corresponding to said first plurality of intensity values to provide a plurality of exposed patch portions on the photoreceptor surface, and (iii) detecting the potential of each of said plurality of exposed patch portions;

a second potential detecting step including the steps of (i) obtaining a second plurality of laser intensity values that increase from an initial value to a predetermined value according to a second interval to provide a second range of intensity values, said second interval being smaller than said first interval and said second range being smaller than said first range, (ii) successively exposing a surface portion of said photoreceptor surface with laser light having intensities corresponding to said second plurality of intensity values to provide a plurality of patch portions on the photoreceptor

surface; and (iii) detecting the potential of each of said plurality of exposed patch portions;
and

a step of setting, as a maximum intensity of the laser exposure mechanism,
a laser intensity with which there has been detected, at said first or said second potential
detecting step, a potential equal to or substantially equal to a predetermined set potential,
wherein said laser intensities corresponding to said second plurality of
intensity values are selected to be close to a laser intensity value corresponding to a
potential detected during said first potential detecting step as closest to said predetermined
set potential.

7. (previously added) A laser intensity adjusting method according to claim 6,
wherein
said second potential detecting step is repeated until there is obtained a
potential equal to or substantially equal to said predetermined set potential.

8. (previously added) A laser intensity adjusting method according to claim 6,
wherein
said laser intensity values obtained at first potential detecting step have
values selected from a plurality of laser intensities obtained by dividing said predetermined
laser intensity value of said first potential detecting step by a first predetermined number.

9. (previously added) A laser intensity adjusting method according to claim 6,
wherein

said laser intensity values obtained at said second potential detecting step
have values selected from a plurality of laser intensities obtained by dividing said
predetermined laser intensity value of said second potential detecting step by a second
predetermined number.

10. (previously added) A laser intensity adjusting method according to claim 8,
wherein

said predetermined laser intensity value is set to a value which is greater
than a suitable maximum intensity.

11. (previously added) A laser intensity adjusting method according to claim 9,
wherein

said predetermined laser intensity value is set to a value which is greater
than a suitable maximum intensity.

12. (new) A laser intensity adjusting method according to claim 6, wherein said
exposed patch portions are spaced apart from each other on the photoreceptor surface.

E'

E' cont.
13. (new) A laser intensity adjusting method according to claim 12, wherein
said exposed patch portions are generally rectangular areas on the photoreceptor.
